



Attorney's Docket No. 5649-842

PATENT

H-6/A
6-25-01
Robertson
and

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re: Kang et al.

Serial No.: 09/665,208

Group Art Unit: 2818

Filed: September 18, 2000

Examiner: D. Nhu

For: APPARATUS FOR FORMING THIN FILM AND METHOD FOR FORMING
CAPACITOR OF SEMICONDUCTOR DEVICE USING THE SAME

Date : June 7, 2001

Commissioner for Patents
Washington, DC 20231

AMENDMENT

Sir:

This Amendment is responsive to the Restriction Requirement of May 16, 2001.

In the Title:

In all occurrences: please delete "AND METHOD FOR FORMING CAPACITOR
OF SEMICONDUCTOR DEVICE USING THE SAME".

In the Claims:

Please cancel Claims 1-22, without prejudice to the filing of a divisional application.

REMARKS

In response to the Restriction Requirement of May 16, 2001, Applicants hereby elect
Invention II, corresponding to Claims 23-44, drawn to an apparatus for forming a thin film on
a substrate. Applicants have canceled Invention I, corresponding to Claims 1-22, drawn to a
method of forming a capacitor on a substrate. This cancellation is being done without
prejudice to the filing of a divisional application for these claims.

Applicants are not traversing the restriction requirement, because Applicants agree
that unpatentability of the apparatus of Invention II would not necessarily imply
unpatentability of the method of Invention I.

The title has been changed to conform to cancellation of the method claims.